Amendments to the Specification

Please replace the paragraph beginning on page 1, line 17, with the following rewritten paragraph:

A liquid drop ejecting head which vibrates a transducer for ejecting a liquid drop by expanding and contracting the piezoelectric transducer is used in a liquid drop ejecting device which is called an ink jet printer which is used for a manufacturing device for a liquid crystal display panel and a printing device of a computer terminal. The piezoelectric transducer is formed by, for example, a piezo (PZT)-element. The piezo-element expands and contracts a driving waveform which is inputted thereto (for example, a voltage waveform).

Please replace the paragraph beginning on page 15, line 11, with the following rewritten paragraph:

Here, the micro-vibration ~~waveform~~ waveforms are categorized in following four waveforms according to a timing at which the micro-vibration waveform is applied to the piezoelectric transducer 30. That is, the micro-vibration ~~waveform~~ waveforms are categorized in the four waveforms such as a normal micro-vibration waveform for always causing a micro-vibration on the piezoelectric transducer 30 under condition that the liquid drop ejecting device is turned on, a pre-ejection micro-vibration waveform for causing a micro-vibration on the piezoelectric transducer 30 before ejecting the liquid drop, a micro-vibration waveform during the ejection for causing a micro-vibration on the piezoelectric transducer 30 during the ejection of the liquid drop, and a post-ejection micro-vibration waveform for causing a micro-vibration on the piezoelectric transducer 30 after the liquid drop is ejected. Whether the ejection waveform or the micro-vibration waveform is applied to the liquid drop ejecting head 4 are determined by changing the address value (A0 to A3) which is outputted from the CPU 20 to the control IC 10 so as to change the inclination of the waveform and generate the micro-vibration waveform.

Please replace the paragraph beginning on page 16, line 2, with the following rewritten paragraph:

FIG. 2 is a timing chart at every ~~terminals~~ terminal in the control IC 10. Here, an RST terminal is omitted in FIG. 2 because the RST terminal does not relate to this operation directly. In the drawing, a COM signal indicates an output line of the driving waveform. Signal lines A0 to A3 indicate an address input line. A signal line CLK 1 signal indicates a latch signal which latches the address in a standing portions. A signal line CLK 2 indicates an output timing signal for the driving waveform. A driving waveform is outputted from the COM terminal so as to synchronize the standing portion of the CLK 2.

Please replace the paragraph beginning on page 10, line 15, with the following rewritten paragraph:

~~FIrst,~~ First, the CPU 20 starts to output the CLK 2 signal having a frequency TCLK 2 to the control IC 10 at timing t0. The CPU 20 outputs the CLK 1 signal at timing t1 and latches the address 1. Here, an output timing for the CLK 1 signal is incorporated in an ROM as a timing data software. The CPU 20 outputs the CLK 1 signal at such a timing and latches the variation amount of voltage $\Delta V1$. By doing this, an electric potential at the COM terminal increases by $\Delta V1$ so as to synchronize with the standing portion (timing t1) of the CLK 2 signal. Similarly, the CPU 20 latches the addresses 2 to 4 by the CLK 1 signal at timings t2 to t4; thus, an electric potential at each COM terminal increase by $\Delta V2$ to $\Delta V4$.

Please replace the paragraph beginning on page 17, line 17, with the following rewritten paragraph:

Therefore, according to a device for driving a liquid drop ejecting head, it is possible to ~~ddrive~~ drive the piezoelectric transducer 30 by a waveform which is entirely a gradual curve in a macro-point; therefore, it is possible to reduce more physical load and a more thermal load which is caused by the physical load than in a case in which the liquid drop

ejecting head is driven by a trapezoid square waveform. Therefore, it is possible to extend a fatigue life of the piezoelectric transducer 30 by restricting the deterioration in the piezoelectric transducer 30. Therefore, it is possible to eject the liquid drop stably for a longer time from the liquid drop ejecting head by a device for driving a liquid drop ejecting head according to the present embodiment.

Please replace the paragraph beginning on page 24, line 1, with the following rewritten paragraph:

Here, a structure of the device 1 for forming a layer according to the present invention is not limited to a structure shown in FIG. 5. It is not necessary that a structure in the liquid drop ejecting head 4 is limited to a structure that the liquid drop ejecting head 4 is provided with three ~~heads 4a . . . .~~ heads 4a.

Please replace the paragraph beginning on page 27, line 24, with the following rewritten paragraph:

Next, after an interlayer insulating layer 230 is formed, contact holes 232 and 234 are formed as shown in FIG. 10D. Consequently, ~~a~~ relay electrodes 236 and 238 are embedded in the contact holes 232 and 234.

Please replace the paragraph beginning on page 31, line 6, with the following rewritten paragraph:

For such a precursor, for example, a precursor of PPV (poly (p-phenylenevinylene)) or its derivative is preferable. A precursor of PPV or its derivative ~~are~~ is soluble in a water or an organic solution. Also, the precursor of PPV or its derivative can be formed in a polymer manner; therefore, it is possible to realize a high quality thin film from an optical point of view. Furthermore, PPV emits an intense illumination, and the PPV is a conductive polymer moieties which are non-localized on a polymer chain; therefore, it is possible to realize a high quality organic EL element.

Please replace the paragraph beginning on page 38, line 11, with the following rewritten paragraph:

Here, the present invention is not limited to the above embodiments. The present invention can be used for manufacturing other devices. Various ~~modification~~ modifications can be made also with in a scope of essential features of the present invention. For example, it is possible to form a film which forms a metal wiring by ejecting a liquid member which contains a metal particle on a required surface from a device for driving a liquid drop ejecting head according to the above embodiments. By doing this, it is possible to form a film which forms a metal wiring stably for a longer time; therefore, it is possible to produce a metal wiring which is made from a thin film of which thickness, flatness, disposition are controlled more precisely than a conventional case, such as a metal wiring in which disconnection ratio is low and highly dense disposition is possible cheaply.

Please replace the Abstract with the attached amended Abstract.